microMARK[™] MCF RXe 200

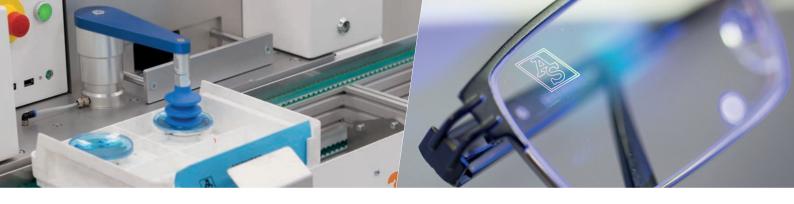
ADVANCED EFFICIENCY IN EXCIMER LASER MARKING

3D-Micromac's laser system microMARK[™] RXe has revolutionized the efficiency of blocked lens engraving by using excimer lasers. Equipped with an optimized optical components setup and a large-sized magnification ratio, this new generation of RX marking devices offers an increased depth of focus at lowest laser power operation on all materials. Customers benefit from low investment and small operating costs.

HIGHLIGHTS

- High-quality engraving
- Accurate contrast adjustment
- Low investment and operating costs
- Reliable process stability
- Smallest excimer system footprint available on the market





microMARK[™] MCF RXe 200 - SYSTEM CONFIGURATION



Benefits:

- High-quality engraving with accurate contrast adjustment on a variety of spectacle lenses and coatings
- Smallest required space on the market
- Low investment and operating costs
- Easy retrofit of automated handling system at customer's site on request

Suitable for	 Technical marking of spectacle lenses Blocked lenses (mineral, plastic) with a maximum size of 80 mm x 35 mm (D x H above block reference) Branding functionality for unblocked lenses on request
Productivity	150 blocked lenses per hour with automatic handling
System accuracy	• ± 0.1 mm
Laser source	Industrial-proven long life excimer laser source 193 nm
Beam delivery unit	 Galvanometer scanner with mirror deflecting system Marking field of Ø 80 mm Power management Permanent nitrogen beam path purging
Software	 Proven ULM software version 4.0.0.0 (or higher), VCA/OMA interface prepared for the main surfacing line manufacturer Remote connection to client included
Options	Automatic handling system
Dimensions	• 960 x 600 x 1,200 mm ³ (W x H x D) (manual and automated system)
Safety	Laser class 1

Other configurations on request.